



MS AF
REPLY UNDER
37 C.F.R. § 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1765
PATENT
3430-0149P

*do not
enter
X168
2/2/05*

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Jeong-Jin KIM et al. Conf. No.: 5548
Appl. No.: 09/727,516 Group: 1765
Filed: December 4, 2000 Examiner: A. K. ALANKO
For: APPARATUS FOR AND METHOD OF ETCHING AND
CLEANING OBJECTS

*Entered
PER. RCE
Request
W.M.
3/11/05*

AMENDMENT UNDER 37 C.F.R. § 1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 21, 2005

Sir:

In response to the Examiner's Final Office Action dated September 21, 2004, the response for which having been extended one (1) month to January 21, 2005, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

This Amendment includes a Claim Set As Amended and Remarks.

01/25/2005 NABED1 00000129 09727516

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120.00 UP